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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10027823	FILING DATE 12/21/2001	CLASS 216	SUBCLASS 433	GAU 4746	EXAMINER 15
**APPLICANTS: Petrucci Joseph; 433 8 1763 1765 (MCM, K)					
**CONTINUING DATA VERIFIED: none K-CC					
** FOREIGN APPLICATIONS VERIFIED: none K-CC					
PG-PUB <input type="checkbox"/>		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no				ATTORNEY DOCKET NO	
35 USC 119 conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no				SC0268WD	
Verified and Acknowledged Examiners's initials K-CC					
TITLE : Method and system for determining a performance of plasma etch equipment					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
ISSUE FEE		Assistant Examiner	
Amount Due	Date Paid	Primary Examiner	
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	
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